



11-9-04

LFW

PTO/SB/21 (03-03)

Approved for use through 04/30/2003. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

TRANSMITTAL FORM (to be used for all correspondence after initial filing)	Application Number	10/636,038
	Filing Date	August 6, 2003
	First Named Inventor	Gurtej Sandhu
	Art Unit	2812
	Examiner Name	Unkonwn
Total Number of Pages in This Submission	Attorney Docket Number	MI22-2194

ENCLOSURES (Check all that apply)		
<input type="checkbox"/> Fee Transmittal Form <input type="checkbox"/> Fee Attached <input type="checkbox"/> Amendment/Reply <input type="checkbox"/> After Final <input type="checkbox"/> Affidavits/declaration(s) <input type="checkbox"/> Extension of Time Request <input type="checkbox"/> Express Abandonment Request <input checked="" type="checkbox"/> Information Disclosure Statement <input type="checkbox"/> Certified Copy of Priority Document(s) <input type="checkbox"/> Response to Missing Parts/Incomplete Application <input type="checkbox"/> Response to Missing Parts under 37 CFR 1.52 or 1.53	<input type="checkbox"/> Drawing(s) <input type="checkbox"/> Licensing-related Papers <input type="checkbox"/> Petition <input type="checkbox"/> Petition to Convert to a Provisional Application <input type="checkbox"/> Power of Attorney, Revocation <input type="checkbox"/> Change of Correspondence Address <input type="checkbox"/> Terminal Disclaimer <input type="checkbox"/> Request for Refund <input type="checkbox"/> CD, Number of CD(s) _____	<input type="checkbox"/> After Allowance Communication to a Technology Center (TC) <input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences <input type="checkbox"/> Appeal Communication to TC (Appeal Notice, Brief, Reply Brief) <input type="checkbox"/> Proprietary Information <input type="checkbox"/> Status Letter <input checked="" type="checkbox"/> Other Enclosure(s) (please identify below): Return Receipt Postcard; Form PTO-1449; Cited References
Remarks <div style="text-align: center; font-size: 2em;">EV372467864</div>		

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT	
Firm or Individual	Mark S. Matkin, Reg No. 32,268 Wells St. John, P.S.
Signature	
Date	11/8/04

CERTIFICATE OF TRANSMISSION/MAILING	
I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as express mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on this date: _____	
Typed or printed	Jim Tidrick
Signature	
Date	11-8-04

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 12 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, Washington, DC 20231.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/636,038
Filing Date August 6, 2003
Inventor Gurtej Sandhu
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Unknown
Attorney's Docket No. MI22-2194
Title: Methods of Forming Material on a Substrate and a Method of Forming a
Field Effect Transistor Gate Oxide on a Substrate

INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

To: Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

EV372467864

From: (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

Dear Sir:

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449 and copies of which are attached.

This Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No.

23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citations of these references are respectfully requested.

Respectfully submitted,

Dated: 11-8-04

By: 

Mark S. Matkin
Reg. No. 32,268

Form PTO-149

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)

ATTY. DOCKET NO.
MI22-2194

SERIAL NO.
10/636,038

APPLICANT
Gurtej Sandhu

FILING DATE
August 6, 2003

GROUP
2812

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AA	6,495,436	12/17/2002	Ahn et al.			
AB	6,762,114	7/13/2004	Chambers			
AC	6,717,226	4/6/2004	Hedge et al.			
AD	6,608,378	8/19/2003	Ahn et al.			
AE	6,579,767	6/17/2003	Park et al.			
AF	6,524,918	2/25/2003	Park et al.			
AG	2004/0023462	2/5/2004	Rotondaro et al.			
AH	2003/0232506	12/18/2003	Metzner et al.			
AI	2001/0029092	10/11/2003	Park et al.			
AJ	2001/0024860	9/27/2001	Park et al.			
AK						
AL						

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AM							
AN							
AO							
AP							
AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

AR	"Surface preparation and post thermal treatment effects on interface properties of thin Al_2O_3 films deposited by ALD;" Chang et al.; Microelectronic Engineering 72, 2004; pp. 326-331.
AS	"Effect Purge time on the properties of HfO_2 films prepared by atomic layer deposition;" Kawahara et al.; IEEE Transactions on Electronics; Vol. E87-C, No. 1; January 2004; pp. 2-8.
AT	"High-k materials for advanced gate stack dielectrics: a comparison of ALCVD and MOCVD as deposition technologies;" Caymax et al.; CMOS Front-End materials and Process Technology Symposium (Mater. Res. Soc. Symposium Proceedings Vol. 765); April 22-24, 2003; 47-58

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-2194SERIAL NO.
10/636,038LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Gurtej SandhuFILING DATE
August 6, 2003GROUP
2812

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

E V 3 7 2 4 6 7 8 6 4

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		"Effect of Hf sources, oxidizing agents, and NH ₃ /Ar plasma on the properties of HfAlO ₄ films prepared by atomic layer deposition;" Kawahara et al.; Japanese Journal of Applied Physics, Vol. 43, No. 7A; July 2004; pp. 4129-4134.
	AS		"Characterization of ultra-thin HfO ₂ gate oxide prepared by using atomic layer deposition;" Tacho et al.; Journal of the Korean Physical Society, Vol. 42, No. 2; February 2003; pp. 272-275.
	AT		
EXAMINER		DATE CONSIDERED	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.